

Development of radiation hard CMOS Active Pixel Sensors for HL-LHC

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Develop depleted radiation hard CMOS Sensors for ATLAS ITK

- ATLAS ITK upgrade for Phase II Pixel detector requires radiation hard sensors, which present CMOS MAPS cannot do (not radiation hard & too slow)
- Started RD to develop commercial CMOS processes to radiation hard sensors through optimized designs, high voltage processes (>100V on chip) and higher resistivity (1000hm*cm to k0hm*cm)



Monolithic solutions benefits:

- Thin & light detector modules
- Simplified assembly and cost advantage for large areas Hybrid solution benefits
- Fast and complex readout in separate digital chip to cope with highest hit rates at smallest radii
- CMOS sensor + analog stages

XFAB SOI 180 nm prototype XTB01 & XTB02

- · Monolithic test chip to investigate transistor and sensor charge collection performance
- Electronics isolated from substrate through oxide (BOX)
- Small collection well (capacitance!) but no competing wells
- Isolating deep P well between CMOS and BOX to avoid backgate effect
- XTB01: 4 different pixel matrices with 3T readout and transistor test structures
- XTB02: Passive diodes to study charge collection ; includes deep p-spray and p-stop



HELR

AMS H18 180nm HV2FEI4 Version 2 & 4

- Matched to ATLAS FEI4 readout chip (50x250μm pixel size) and includes sub-pixel encoding
- Sub-pixel (size 33x125µm) includes Preamp + Shaper + Discriminator

Produced in AMS H18 process:

- $\rho = 10\Omega cm$ with bias 60–100V
- Depletion depth ~10 µm
- Q (theoretical) ~1000 e- by drift
- capacitively coupled to FEI4



HV2FEI4 CCPD Version 2:

- Three pixel types
- Voltage based sub pixel encoding
- First to work after 850 Mrad

HV2FEI4 CCPD Version 4:

- Lower noise
- Pulse length or voltage based sub-pixel encoding

16 col. of 33.3 µm 8 col. of 25 µm



Hemperek, Kishishita, Krüger, NW arxiv

XTB01 (25C)

1412.3973, accepted NIM A

structures to intercept accumulation layer

XFAB Trench SOI 0.18 µm CMOS low-power 1.8/5.0V

- P-type bulk, 4 metal layers,
- Prototype size Size: 5 x 2 mm2
- Wafer size: 8" with high handling wafer resistivity:

•100 Ω cm CZ

- •1 k Ω cm possible
- HV applied from front side up to 300V

Results on XFAB CMOS prototype

- γ-Irradiated up to 700Mrad, annealed after irradiation
- n-irradiated at Triga/Ljubljana up to 5x10¹⁴ n/cm²





- \rightarrow No back-gate effect observed & Electronics shielded from field of sensor diode
- TID leads to BOX charge-up, which creates an accumulation layer in the substrate between DNW and bias-DPW +++++++
 - Increased leakage
 - Reduced max bias voltage
- Implemented p-stop (DPW) to intercept accumulation layer in XTB02
- \rightarrow DPW (P-Stop) reduces leakage and leads to high breakdown voltage
- Signals in Source & Beam tests XFAB XTB01





I. Peric et al., NIM A765 (2014) 172-176

Capacitive coupling to FEI4

- Capacitive readout AMS CMOS sensor to input of ATLAS FEI4 pixel readout chip
- "Capacitive Coupled Pixel Detector" (CCPD)
- Flip chip on SET FC150
- Achieved glue layer thickness of 3µm
- Alignment of 1-1.5µm
- Also demonstrated planarity and thickness on full size FEI4 assemblies (21x18mm) using planar sensors



Charge Collection Studies

Lab characterization before and after irradiation : Edge Transient Current Technique



- Drift and diffusion are distinguished by timing cut at 2.5ns
- \rightarrow In-time signal fraction increases with irradiation
- →Acceptor removal due to irradiation may lead to increased substrate resistivity & depleted area

Beam test results on AMS 180nm

Results on AMS 180nm CCPD



